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2	INZZ	modulator\$1 WITH spac\$3	unrestricted	628	show titles
3	INZZ	diffract\$3 WITH modulator\$1 WITH spac\$3	unrestricted	12	show titles
4	INZZ	diffract\$3 WITH modulator\$1 WITH (spac\$3 OR freqenc\$3 OR pitch\$2)	unrestricted	16	show titles

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- ☐ Classification codes A: Physics, 7
- ☐ Classification codes A: Physics, 8
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Updated Search Query Case No. 10/808,152

414	modulator\$1 with spac\$3 with apart	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB
1	("6714337").PN.	USPAT; USOCR
7	US-5661592-\$.DID. OR US-5841579-\$.DID. OR US-5900637-\$.DID. OR US-6133986-\$.DID. OR US-6312134-\$.DID. OR US-6379867- \$.DID. OR US-6473237-\$.DID.	USPAT
1362	(359/290,291,298).CCLS.	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB
36	((359/290,291,298).CCLS.) and (modulator\$1 with spac\$3 with apart)	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB
1	20030228154	US-PGPUB; USPAT
17	micromirror\$1 with buffer\$1	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB
115	diffract\$3 with modulator\$1 with spac\$3	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB
1	20030058520	US-PGPUB; USPAT
5031	(359/290,291,298,254,292,619,559,224,855,572).CCLS.	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB
192	(345/6).CCLS.	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB
7434	(355/53,67,71).CCLS.	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB
15004	(430/5,22,30,296,322,396).CCLS.	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB
2078	(250/292.22,492.1).CCLS.	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB
26989	S15 or S16 or S17 or S18 or S19	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB

448	modulator\$1 with spac\$3 with apart	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB
62	S20 and S21	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB
251	S20 and (modulator\$1 with spac\$3)	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB
115	diffract\$3 with modulator\$1 with spac\$3	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB
15	S20 and S24	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB
149	diffract\$3 with modulator\$1 with (spac\$3 or freqenc\$3 or pitch\$2)	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB
24	S20 and S26	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB

Search Results Case No. 10/808,152

US 5311360 A	USPAT	Method and apparatus for modulating a light beam	359/572
US 5459610 A	USPAT	Deformable grating apparatus for modulating a light beam and including means for obviating stiction between grating elements and underlying substrate	359/572
US 5541914 A	USPAT	Packet-switched self-routing multistage interconnection network having contention-free fanout, low-loss routing, and fanin buffering to efficiently realize arbitrarily low packet loss	370/427
US 5661592 A	USPAT	Method of making and an apparatus for a flat diffraction grating light valve	359/291
US 5835256 A	USPAT	Reflective spatial light modulator with encapsulated micro mechanical elements	359/291
US 5841579 A	USPAT	Flat diffraction grating light valve	359/572
US 5900637 A	USPAT	Maskless lithography using a multiplexed array of fresnel zone plates	250/492.22
US 5920418 A	USPAT	Diffraction optical modulator and method for producing the same, infrared sensor including such a diffraction optical modulator and method for producing the same, and display device including such a diffraction optical modulator	359/246
US 5949570 A	USPAT	Diffraction optical modulator and method for producing the same, infrared sensor including such a diffraction optical modulator and method for producing the same, and display device including such a diffraction optical modulator	359/291
US 5982553 A	USPAT	Display device incorporating one-dimensional grating light-valve array	359/627
US 6133986 A	USPAT	Microlens scanner for microlithography and wide-field confocal microscopy	355/67
US 6172796 B1	USPAT	Multilevel electro-mechanical grating device and a method for operating a multilevel mechanical and electro-mechanical grating device	359/290
US 6312134 B1	USPAT	Seamless, maskless lithography system using spatial light modulator	359/855
US 6379867 B1	USPAT	Moving exposure system and method for maskless lithography system	430/296
US 6381062 B1	USPAT	Optical data modulation system with self-damped diffraction light modulator	359/291
US 6473237 B2	USPAT	Point array maskless lithography	359/619
US 6639722 B2	USPAT	Stress tuned blazed grating light valve	359/571
US 6646623 B1	USPAT	Three-dimensional display apparatus	345/6
US 20030035189 A1	US-PGPUB	Stress tuned blazed grating light valve	359/254
US 20030228154 A1	US-PGPUB	Multi-array spatial light modulating devices and methods of fabrication	398/183
US 20040196526 A1	US-PGPUB	Loosely-packed two-dimensional modulator arrangement	359/291